



UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: **NAKASUJI, Mamoru et al.**

Serial No.: **09/891,611**

Group Art Unit: **2881**

Filed: **June 27, 2001**

Examiner: **BERMAN, Jack I.**

Confirmation No.: **8874**

For: **INSPECTION SYSTEM BY CHARGED PARTICLE BEAM AND METHOD OF
MANUFACTURING DEVICES USING THE SYSTEM**

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

February 6, 2004

Sir:

In response to the Office Action dated **November 6, 2003**, please amend the above-identified application as follows: